



THE 57TH INTERNATIONAL CONFERENCE ON ELECTRON, ION, AND PHOTON BEAM TECHNOLOGY AND NANOFABRICATION

The Gaylord Opryland Resort and Convention Center Nashville, May 28 – 31, 2013

The **EIPBN** Conference is recognized as the foremost international meeting dedicated to lithographic science and process technology and its use in micro and nanofabrication techniques and their applications. The conference brings together engineers and scientists from industries and universities from all over the world to discuss recent progress and future trends.

Abstracts should be submitted online at www.eipbn.org

Abstracts are limited to one page of text (12 point or larger type) and a second, optional page with up to four figures. Abstract deadline: January 7, 2013

Micrograph Contest: EIPBN offers the opportunity to immortalize your favorite micrograph(s). Categories and previous winners are described on our website.

Limited funds are available to support **student travel**. The Conference Chair must receive a letter requesting support from the student's advisor by May 1, 2013. For helping with housing costs a "Room with another student" option will be available at the Gaylord.

Abstracts representing **high quality original research** are invited in the following areas:

- Extreme UV lithography
- Electron and ion beam lithography
- Advanced optical lithography
- Metrology and imaging
- Resists and resist processing
- Plasma etching and deposition
- Nano-fabrication techniques
- Maskless lithography
- Nano-imprint lithography
- Soft lithography and embossing

Topics in emerging technologies include:

- Nanoscale simulation and modelling
- Nano-photonics
- Patterned media and data storage
- Nano electronics
- Nano-biology
- Micro- and nano-scale MEMS
- Micro- and nano-fluidics
- Self-assembly and directed self-assembly
- Nanofabrication for energy sources
- Atomic and Molecular manipulation

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To add your name to the mailing list, please mail a business card or e-mail to the Conference Chair.

The EIPBN conference is co-sponsored by the American Vacuum Society (www.avs.org), in cooperation with the IEEE Electron Devices, Lasers and Electro-optics Societies and the Optical Society of America.

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